



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter de Groot et al. Art Unit : Unknown  
Serial No. : 10/795,808 Examiner : Unknown  
Filed : March 8, 2004  
Title : PROFILING COMPLEX SURFACE STRUCTURES USING SCANNING  
INTERFEROMETRY

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

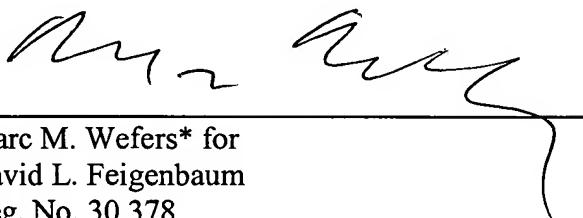
INFORMATION DISCLOSURE STATEMENT

Applicant submits the references listed on the attached form PTO-1449.

This statement is being filed within three months of the filing date of the application or before the receipt of a first Office action on the merits. Please apply any charges or credits to Deposit Account No. 06-1050, referencing Attorney Docket No. 09712-341001.

Respectfully submitted,

Date: 3/31/04



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\*See attached document certifying that Marc M. Wefers has limited recognition to practice before the U.S. Patent and Trademark Office under 37 C.F.R. § 10.9(b).

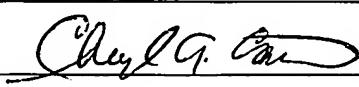
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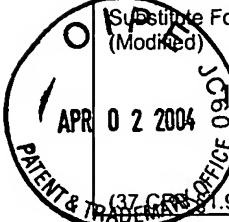
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 Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office		Attorney's Docket No. 09712-341001	Application No.
	<b>Information Disclosure Statement</b> by Applicant (Use several sheets if necessary)		Applicant Peter de Groot et al.	
			Filing Date March 8, 2004	Group Art Unit

### U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	4,576,479	03/18/1986	Downs	356	351	
	AB	4,999,014	03/12/1991	Gold et al.	356	382	
	AC	5,133,601	07/28/1992	Cohen et al.	356	359	
	AD	5,602,643	02/11/1997	Barrett	356	360	
	AE	6,545,763	04/08/2003	Kim et al.	356	503	
	AF	6,597,460	07/22/2003	Groot et al.	356	512	
	AG						
	AH						

### Foreign Patent Documents or Published Foreign Patent Applications

Examiner Initial	Desig. ID	Document Number	Publication Date	Country or Patent Office	Class	Subclass	Translation	
							Yes	No
	AI	0 397 388 A2	11/14/1990	EPO	G01B	11/06		
	AJ	0 549 166 A2	06/30/1993	EPO	G01B	11/06		
	AK							
	AL							

### Other Documents (include Author, Title, Date, and Place of Publication)

Examiner Initial	Desig. ID	Document
	AM	Dresel, Thomas et al., "Three-dimensional sensing of rough surfaces by coherence radar", <u>Applied Optics</u> , Vol. 31, No. 7, pp. 919-925 (March 1, 1992)
	AN	Feke, Gilbert D. et al., "Interferometric back focal plane microellipsometry", <u>Applied Optics</u> , Vol. 37, No. 10, pp. 1796-1802 (April 1, 1998)
	AO	Kim, Seung-Woo et al., "Thickness-profile measurement of transparent thin-film layers by white-light scanning interferometry", <u>Applied Optics</u> , Vol. 38, No. 28, pp. 5968-5973 (October 1, 1999)
	AP	Kino, Gordon S. et al., "Mirau correlation microscope", <u>Applied Optics</u> , Vol. 29, No. 26, pp. 3775-3783 (September 10, 1990)
	AQ	Pelligrand, S. et al., "Mesures 3D de topographies et de vibrations a l'echelle (sub)micrometrique par microscopie optique interferometrique", <u>Proc. Club CMOI, Methodes et Techniques Optiques pour l'Industrie</u> (2002)
	AR	Pluta, Maksymilian, "Advanced Light Microscopy", Vol. 3, (Elsevier, Amsterdam, 1993) pp. 265-271
	AS	Rosencwaig, Allan et al., "Beam profile reflectometry: A new technique for dielectric film measurements", <u>Applied Physics Letters</u> , Vol. 60, No. 11, pp. 1301-1303 (March 16, 1992)

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

Substitute Form PTO-1449  
(Modified)U.S. Department of Commerce  
Patent and Trademark OfficeAttorney's Docket No.  
09712-341001

Application No.

Applicant  
Peter de Groot et al.Filing Date  
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Group Art Unit

**Information Disclosure Statement  
by Applicant**  
(Use several sheets if necessary)

<b>Other Documents (include Author, Title, Date, and Place of Publication)</b>		
Examiner Initial	Desig. ID	Document
	BA	Sandoz, Patrick "Wavelet transform as a processing tool in white-light interferometry", <u>Optics Letters</u> , Vol. 22, No. 14, pp. 1065-1067 (July 15, 1997)
	BB	Shatalin, S.V. et al., "Reflection conoscopy and micro-ellipsometry of isotropic thin film structures", <u>Journal of Microscopy</u> , Vol. 179, Part 3, pp. 241-252 (September, 1995)
	BC	
	BD	

Examiner Signature	Date Considered
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